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EXPEDITED PROCEDURE - EXAMINING GROUP 1763

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PATENT

Attorney Docket No.: 016301-
021300US

Client Ref.: 2119

on July 10, 2000

TOWNSEND and TOWNSEND and CREW LLP

By

Andrea S. Beck

#16
7/18/00
MM

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Karl Littau, et al.

Application No.: 08/893,917

Filed: July 11, 1997

For: Remote Plasma Cleaning Source Having
Reduced Reactivity With a Substrate Processing
Chamber

Examiner: Rudy Zervigon
Art Unit: 1763

NOTICE OF APPEAL

EXPEDITED PROCEDURE
EXAMINING GROUP 1763

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Commissioner of Patents
and Trademarks
Washington, D.C. 20231

Sir:

Applicant hereby appeals to the Board of Appeals and Interferences from the Examiner's decision dated March 10, 2000 rejecting claims 1-21.

A Petition to extend time to respond:

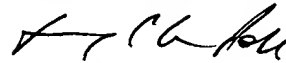
1. ☒ for one month extension of time is enclosed.
2. **Please enter the amendment filed on May 4, 200 for the above referenced application.**
3. ☒ Please charge the filing fee of \$300 for this Appeal to Deposit Account No. 20-1430 of the Undersigned. This Notice is submitted in triplicate.



Karl Littau, et al.
Application No.: 08/893,917
Page 2

PATENT

Respectfully submitted,



Chun-Pok Leung
Reg. No. 41,405

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